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In the Claims:

(original) A semiconductor device comprising:
 a substrate; and

at least one MOSFET adjacent said substrate and comprising

a superlattice channel including a plurality of stacked groups of layers, and

source and drain regions laterally adjacent said superlattice channel and a gate overlying said superlattice channel for causing transport of charge carriers through said superlattice channel in a parallel direction relative to the stacked groups of layers,

each group of layers of said superlattice channel comprising a plurality of stacked base semiconductor monolayers defining a base semiconductor portion and an energy band-modifying layer thereon,

said energy-band modifying layer comprising at least one non-semiconductor monolayer constrained within a crystal lattice of adjacent base semiconductor portions so that said superlattice channel has a higher charge carrier mobility in the parallel direction than would otherwise be present.

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2. (original) A semiconductor device according to Claim 1 wherein said superlattice channel has a common energy band structure therein.

- 3. (original) A semiconductor device according to Claim 1 wherein the charge carriers having the higher mobility comprise at least one of electrons and holes.
- 4. (original) A semiconductor device according to Claim 1 wherein each base semiconductor portion comprises silicon.
- 5. (original) A semiconductor device according to Claim 1 wherein each energy band-modifying layer comprises oxygen.
- 6. (original) A semiconductor device according to Claim 1 wherein each energy band-modifying layer is a single monolayer thick.
- 7. (original) A semiconductor device according to Claim 1 wherein each base semiconductor portion is less than eight monolayers thick.

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8. (original) A semiconductor device according to Claim 1 wherein each base semiconductor portion is two to six monolayers thick.

- 9. (original) A semiconductor device according to Claim 1 wherein said superlattice further has a substantially direct energy bandgap.
- 10. (original) A semiconductor device according to Claim 1 wherein said superlattice further comprises a base semiconductor cap layer on an uppermost group of layers.
- 11. (currently amended) A semiconductor device according to Claim 11 10 wherein said gate comprises a gate electrode layer and a gate dielectric layer between said gate electrode layer and said base semiconductor cap layer.
- 12. (original) A semiconductor device according to Claim 1 wherein all of said base semiconductor portions are a same number of monolayers thick.
- 13. (original) A semiconductor device according to Claim 1 wherein at least some of said base semiconductor portions are a different number of monolayers thick.

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14. (original) A semiconductor device according to Claim 1 wherein all of said base semiconductor portions are a different number of monolayers thick.

- 15. (original) A semiconductor device according to Claim 1 wherein each non-semiconductor monolayer is thermally stable through deposition of a next layer.
- 16. (original) A semiconductor device according to Claim 1 wherein each base semiconductor portion comprises a base semiconductor selected from the group consisting of Group IV semiconductors, Group III-V semiconductors, and Group II-VI semiconductors.
- 17. (original) A semiconductor device according to Claim 1 wherein each energy band-modifying layer comprises a non-semiconductor selected from the group consisting of oxygen, nitrogen, fluorine, and carbon-oxygen.
- 18. (original) A semiconductor device according to Claim 1 wherein the higher mobility results from a lower conductivity effective mass for the charge carriers in the parallel direction than would otherwise occur.

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19. (original) A semiconductor device according to Claim 18 wherein the lower conductivity effective mass is less than two-thirds the conductivity effective mass that would otherwise occur.

- 20. (original) A semiconductor device according to Claim 1 wherein said superlattice further comprises at least one type of conductivity dopant therein.
 - 21. (original) A semiconductor device comprising: a substrate; and
- at least one MOSFET adjacent said substrate and comprising

a superlattice channel comprising a plurality of stacked groups of layers, and

source and drain regions laterally adjacent said superlattice channel and a gate overlying said superlattice channel for causing transport of charge carriers through said superlattice channel in a parallel direction relative to the stacked groups of layers,

each group of layers of said superlattice channel comprising a plurality of stacked silicon atomic layers

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defining a silicon portion and an energy band-modifying layer thereon,

said energy-band modifying layer comprising at least one oxygen atomic layer constrained within a crystal lattice of adjacent silicon portions so that said superlattice has a higher charge carrier mobility than would otherwise be present.

- 22. (original) A semiconductor device according to Claim 21 wherein said superlattice channel has a common energy band structure therein.
- 23. (original) A semiconductor device according to Claim 21 wherein the charge carriers having the lower conductivity effective mass comprise at least one of electrons and holes.
- 24. (original) A semiconductor device according to Claim 21 wherein each energy band-modifying layer is a single atomic layer thick.
- 25. (original) A semiconductor device according to Claim 21 wherein each silicon portion is less than eight atomic layers thick.

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- 26. (original) A semiconductor device according to Claim 21 wherein each silicon portion is two to six atomic layers thick.
- 27. (original) A semiconductor device according to Claim 21 wherein said superlattice channel further has a substantially direct energy bandgap.
- 28. (original) A semiconductor device according to Claim 21 wherein said superlattice channel further comprises a silicon cap layer on an uppermost group of layers.
- 29. (currently amended) A semiconductor device according to Claim 29 28 wherein said gate comprises a gate electrode layer and a gate dielectric layer between said gate electrode layer and said base semiconductor cap layer.
- 30. (original) A semiconductor device according to Claim 21 wherein all of said silicon portions are a same number of atomic layers thick.

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- 31. (original) A semiconductor device according to Claim 21 wherein at least some of said silicon portions are a different number of atomic layers thick.
- 32. (original) A semiconductor device according to Claim 21 wherein all of said silicon portions are a different number of atomic layers thick.
- 33. (original) A semiconductor device according to Claim 21 wherein the higher charge carrier mobility results from a lower conductivity effective mass for charge carriers in the parallel direction than would otherwise occur.
- 34. (original) A semiconductor device according to Claim 21 wherein said superlattice channel further comprises at least one type of conductivity dopant therein.
 - 35. (original) A semiconductor device comprising: a substrate; and

at least one MOSFET adjacent said substrate and comprising

a superlattice channel comprising a plurality of stacked groups of layers, and

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source and drain regions laterally adjacent said superlattice channel and a gate overlying said superlattice channel for causing transport of charge carriers through said superlattice channel in a parallel direction relative to the stacked groups of layers,

each group of layers of said superlattice channel comprising less than eight stacked base semiconductor monolayers defining a base semiconductor portion and an energy band-modifying layer thereon,

said energy-band modifying layer comprising a single non-semiconductor monolayer constrained within a crystal lattice of adjacent base semiconductor portions so that said superlattice has a high charge carrier mobility in the parallel direction than would otherwise be present.

- 36. (original) A semiconductor device according to Claim 35 wherein said superlattice channel has a common energy band structure therein.
- 37. (original) A semiconductor device according to Claim 35 wherein the charge carriers having the higher mobility comprise at least one of electrons and holes.

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38. (original) A semiconductor device according to Claim 35 wherein said superlattice channel further has a substantially direct energy bandgap.

- 39. (original) A semiconductor device according to Claim 35 wherein said superlattice channel further comprises a base semiconductor cap layer on an uppermost group of layers.
- 40. (currently amended) A semiconductor device according to Claim 40 39 wherein said gate comprises a gate electrode layer and a gate dielectric layer between said gate electrode layer and said base semiconductor cap layer.
- 41. (original) A semiconductor device according to Claim 35 wherein all of said base semiconductor portions are a same number of monolayers thick.
- 42. (original) A semiconductor device according to Claim 35 wherein at least some of said base semiconductor portions are a different number of monolayers thick.
- 43. (original) A semiconductor device according to Claim 35 wherein all of said base semiconductor portions are a different number of monolayers thick.

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44. (original) A semiconductor device according to Claim 35 wherein the higher charge carrier mobility results from a lower conductivity effective mass for charge carriers in the parallel direction than would otherwise occur.

- 45. (original) A semiconductor device according to Claim 35 wherein said superlattice channel further comprises at least one type of conductivity dopant therein.
 - 46. (original) A semiconductor device comprising: a substrate; and

at least one MOSFET adjacent said substrate and comprising

a superlattice channel comprising a plurality of stacked groups of layers, and

source and drain regions laterally adjacent said superlattice channel and a gate overlying said superlattice channel for causing transport of charge carriers through said superlattice channel in a parallel direction relative to the stacked groups of layers,

each group of layers of said superlattice channel comprising less than eight stacked silicon atomic layers

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defining a silicon portion and an energy band-modifying layer thereon,

said energy-band modifying layer comprising a single oxygen atomic layer constrained within a crystal lattice of adjacent silicon portions.

- 47. (original) A semiconductor device according to Claim 46 wherein said superlattice channel further comprises a base semiconductor cap layer on an uppermost group of layers.
- 48. (original) A semiconductor device according to Claim 47 wherein said gate comprises a gate electrode layer and a gate dielectric layer between said gate electrode layer and said base semiconductor cap layer.
- 49. (original) A semiconductor device according to Claim 46 wherein all of said base semiconductor portions are a same number of atomic layers thick.
- 50. (original) A semiconductor device according to Claim 46 wherein at least some of said base semiconductor portions are a different number of atomic layers thick.

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51. (original) A semiconductor device according to Claim 46 wherein all of said base semiconductor portions are a different number of atomic layers thick.

- 52. (original) A semiconductor device according to Claim 46 wherein said superlattice channel further comprises at least one type of conductivity dopant therein.
 - 53. (original) A semiconductor device comprising: a substrate; and

at least one MOSFET adjacent said substrate and comprising

a superlattice channel including a plurality of stacked groups of layers, and

source and drain regions laterally adjacent said superlattice channel and a gate overlying said superlattice channel for causing transport of charge carriers through said superlattice channel in a parallel direction relative to the stacked groups of layers,

each group of layers of said superlattice channel comprising a plurality of stacked base semiconductor monolayers defining a base semiconductor portion and an energy band-modifying layer thereon,

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said energy-band modifying layer comprising at least one non-semiconductor monolayer constrained within a crystal lattice of adjacent base semiconductor portions so that said superlattice channel has a lower conductivity effective mass for charge carriers in the parallel direction than would otherwise be present.

- 54. (original) A semiconductor device according to Claim 53 wherein said superlattice channel has a common energy band structure therein.
- 55. (original) A semiconductor device according to Claim 53 wherein the charge carriers having the lower conductivity effective mass comprise at least one of electrons and holes.
- 56. (original) A semiconductor device according to Claim 53 wherein each base semiconductor portion comprises silicon.
- 57. (original) A semiconductor device according to Claim 53 wherein each energy band-modifying layer comprises oxygen.

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58. (original) A semiconductor device according to Claim 53 wherein each energy band-modifying layer is a single monolayer thick.

- 59. (original) A semiconductor device according to Claim 53 wherein each base semiconductor portion is less than eight monolayers thick.
- 60. (original) A semiconductor device according to Claim 53 wherein each base semiconductor portion is two to six monolayers thick.
- 61. (original) A semiconductor device according to Claim 53 wherein said superlattice further has a substantially direct energy bandgap.
- 62. (original) A semiconductor device according to Claim 53 wherein said superlattice further comprises a base semiconductor cap layer on an uppermost group of layers.
- 63. (original) A semiconductor device according to Claim 62 wherein said gate comprises a gate electrode layer and a gate dielectric layer between said gate electrode layer and said base semiconductor cap layer.

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- 64. (original) A semiconductor device according to Claim 53 wherein all of said base semiconductor portions are a same number of monolayers thick.
- 65. (original) A semiconductor device according to Claim 53 wherein at least some of said base semiconductor portions are a different number of monolayers thick.
- 66. (original) A semiconductor device according to Claim 53 wherein all of said base semiconductor portions are a different number of monolayers thick.
- 67. (original) A semiconductor device according to Claim 53 wherein each non-semiconductor monolayer is thermally stable through deposition of a next layer.
- 68. (original) A semiconductor device according to Claim 53 wherein each base semiconductor portion comprises a base semiconductor selected from the group consisting of Group IV semiconductors, Group III-V semiconductors, and Group II-VI semiconductors.

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- 69. (original) A semiconductor device according to Claim 53 wherein each energy band-modifying layer comprises a non-semiconductor selected from the group consisting of oxygen, nitrogen, fluorine, and carbon-oxygen.
- 70. (original) A semiconductor device according to Claim 53 wherein the lower conductivity effective mass is less than two-thirds the conductivity effective mass that would otherwise occur.
- 71. (original) A semiconductor device according to Claim 53 wherein said superlattice further comprises at least one type of conductivity dopant therein.